

SW Test Workshop Semiconductor Wafer Test Workshop

# CNT-Based Microspring Probe Design – Towards small pitch (<50 µm) applications

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#### **Overview**

## • Motivation

- Why Carbon Nanotubes?
- Photo-thermal CVD Deposition and Characterisation of CNTs
- Functionalisation of CNTs
- Contacting Carbon/Electromechanical Testing
- Conclusions
- Future work

#### **Motivation**



https://www.nytimes.com/2015/09/27/technology/smaller-fastercheaper-over-the-future-of-computer-chips.html https://www.prnewswire.com/news-releases/microprocessor-and-gpumarket-expected-to-be-worth-usd-8369-billion-by-2022-300466716.html

### **Motivation**

• 200 µm pitch microspring probes

500.0 um

50.0 µm

Can we replace these with CNTs?

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500 µ

## **Carbon Nanotubes (CNTs)**

#### Overview and types of CNTs

- A SWCNT is a graphene sheet rolled over into a cylinder.
- The nature of the wrapping (chirality) and the diameter of the tubes gives different electrical properties
- Metallic  $E_g = 0$ , semi-metallic  $E_g < 100 \text{mV}$  and semiconducting  $E_g = 0.7 \text{ eV/d}_t$
- Synthesis of CNTs can be done by different methods but the main deposition method is catalytic CVD method.



Dai H 2002 Carbon nanotubes: Opportunities and challenges Surf. Sci. 500 218–41

#### **Carbon Nanotubes (CNTs)**

#### Quantised Electrical Conductance of CNTs

 $G_0$ ,  $(\sim \frac{1}{12.9} K \Omega^{-1})$  is the quantum conductance of a one-dimensional channel

$$G_o = \frac{2e^2}{h}$$

General formula for conductance, Landauer formula  $G = G_0 T M(\mu)$ 

For SWCNTs with **perfect metal contacts** (T = 1), the resistance value can be found to be 6.45 K $\Omega$ 

**Classical Contact resistance in CNTs** 

$$R = R_{contacts} + R_{tube}$$

 $\overline{R}_{contacts} \ge h/4 e^{2^{7}}$ 

Theoretical limit, no scattering at the interface

**Ballistic conduction** 

 $R_{tube} = (h/4 e^2)(L/l)$ 

the tube

*L* is the tube length, *l* is the mean free path

where *T* is the transmission probability per

channel and  $M(\mu)$  is the # of conducting channels

Depends on the chirality and the diameter of

When  $L \gg l$ ; the resistance deviates from ballistic and becomes more length dependent.

#### **Photo-Thermal CVD Deposition of CNTs**

Synthesis of Vertically-Aligned CNTs



The PTCVD system consists of :

- An optical head as the source of optical energy applied from the top
- A substrate holder cooled from the bottom to keep substrate temperature below 450 °C



## **Fabrication of CNT probe structures**



- Selective deposition of the catalyst by photolithography
- 2304 as-grown CNT probes with 50 µm pitch in a 2.4 x 2.4 cm area

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2 µm

#### **Characterisation and Functionalisation of CNT probes**



- **RBM:** vibrations in the radial direction
  - $w_{RBM} = \frac{A}{d_t} + B$ the frequency  $\implies$  the diameter
- **D Band:** disorder induced

- **G Band:** longitudinal vibrations, indication of crystallinity
- **2D Band:** Long Range Order

#### **Characterisation and Functionalisation of CNT probes** Densification

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### **Electromechanical Testing Rig Setup**





- Load Cell Sensitivity: ± 1 mN
- Max Load: ~3000 mN
- Displacement Laser Measuring Range: ± 5 mm
- Motorised Stage Resolution: ± 1.5 μm

### **Electromechanical Testing Rig Setup**



- Arrays of Au metallised CNT microspring probes with 200 and 400  $\mu m$  pitches on Si
- As-grown vertically aligned CNT probes on alumina substrate with various pitches
  - Probe lengths up to 750-800  $\mu m$

## Approach

Electromechanical Testing of metal-CNT probes

#### Cyclic Loading

- Reproducibility

- Repeatability

#### Loading until Failure

- Compliance

- Load/Displacement

#### **Constant Loading**

- Current Carrying Capability

# **Results – Cyclic Loading**



## **Results – Increasing Loading**



Pd Metallised 400 micron pitch sample 125 micron travel, increasing load – 2.5 µm/travel 500 cycle - 25 µm travel

# **Results – Increasing Loading - Au**



10.0 µm

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# **Results – Increasing Loading - Pd**



#### **Results – Directional deposition**



DC - Sputtered Pd

E-beam Evaporated Au

#### **Results – Constant Load**



**Pd:** 400 micron and 200 micron pitch probe

Au: 400 micron and 200 micron pitch probe

# Conclusion

- Microspring probe structures ( up to 750  $\mu m$  ) based on metallised vertically-aligned CNT are demonstrated
- Pitch can be controlled by selectively patterning the catalyst for CNT deposition
- Reproducible, low contact resistance (<1  $\Omega$ ) with compliances up to 50 $\mu$ m
- Processes such as; densification, functionalisation allow tunability of the as grown probes
- Higher contact resistance;
  - Work function mismatch
  - Defects and impurities near the interface
  - Poor wetting
  - Resistivity of Carbon

## **Future work**

- Work towards reproducible 100,000 cycles before failure
- Decrease the contact resistance to below 0.2  $\Omega$
- CNT forests as interconnects?
- Transfer printing techniques to form more stable contacts
- High temperature probing applications;
  - CNTs are very stable at high temperatures

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